

Wednesday Morning, October 31, 2012

Exhibitor Technology Spotlight

Room: West Hall - Session EW-WeM

Exhibitor Technology Spotlight

Moderator: D. Surman, Kratos Analytical Inc.

10:20am **EW-WeM8 Mass Spectrometer Now Supports Process Control.** *S. Lass*, Brooks Automation

With the introduction of the 835 Vacuum Quality Monitor and 835 Differential Pumping System, Granville-Phillips has added key control features and extended the operating pressure range to enable process monitoring and control. Driving outputs from user-defined equations which utilize the partial pressures from this gas analysis system provides the ability to start and stop a process based on specific conditions. And differential pumping allows operation at both process and base-out pressures. Process pressure operation together with the features required for process control will be covered.

Authors Index

Bold page numbers indicate the presenter

— **L** —

Lass, S.: EW-WeM8, **1**